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PPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO
10/769,047	01/30/2004	S. Brad Herner	MA-100-I	7037
33971 759	90 02/06/2006		EXAMINER	
MATRIX SEMICONDUCTOR, INC.			CHEN, BRET P	
3230 SCOTT BO			ART UNIT	PAPER NUMBER
	,		1762	

DATE MAILED: 02/06/2006

Please find below and/or attached an Office communication concerning this application or proceeding.

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,	Application No.	Applicant(s)	
	10/769,047	HERNER ET AL.	•
Office Action Summary	Examiner	Art Unit	
	B. Chen	1762	
The MAILING DATE of this communication Period for Reply	n appears on the cover sheet w	ith the correspondence address	5
A SHORTENED STATUTORY PERIOD FOR R WHICHEVER IS LONGER, FROM THE MAILIN  - Extensions of time may be available under the provisions of 37 C after SIX (6) MONTHS from the mailing date of this communication.  - If NO period for reply is specified above, the maximum statutory - Failure to reply within the set or extended period for reply will, by Any reply received by the Office later than three months after the earned patent term adjustment. See 37 CFR 1.704(b).	NG DATE OF THIS COMMUNI FR 1.136(a). In no event, however, may a on. period will apply and will expire SIX (6) MOI statute, cause the application to become A	CATION. reply be timely filed  NTHS from the mailing date of this commun BANDONED (35 U.S.C. § 133).	
Status			
3) Since this application is in condition for al	This action is non-final.	•	its is
closed in accordance with the practice un	der <i>Ex parte Quayle</i> , 1935 C.E	D. 11, 453 O.G. 213.	
Disposition of Claims			
4) ☐ Claim(s) 1-16 is/are pending in the application Papers	hdrawn from consideration. and/or election requirement.		
9)☐ The specification is objected to by the Exa		•	
10)☐ The drawing(s) filed on is/are: a)☐	·	- T	
Applicant may not request that any objection to			
Replacement drawing sheet(s) including the c	•	•	
Priority under 35 U.S.C. § 119			
12) Acknowledgment is made of a claim for for a) All b) Some * c) None of:  1. Certified copies of the priority docur 2. Certified copies of the priority docur 3. Copies of the certified copies of the application from the International Br	ments have been received. ments have been received in A priority documents have been ureau (PCT Rule 17.2(a)).	opplication No received in this National Stage	e
Attachment(s)  1) Notice of References Cited (PTO-892)		Summary (PTO-413)	
Notice of Draftsperson's Patent Drawing Review (PTO-94     Information Disclosure Statement(s) (PTO-1449 or PTO/S Paper No(s)/Mail Date		s)/Mail Date nformal Patent Application (PTO-152)	

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#### **DETAILED ACTION**

Claims 1-16 are pending in this application, which is a DIV of Serial Number 10/441,601 now US Patent 6,815,077.

#### Oath/Declaration

The oath or declaration is defective. A new oath or declaration in compliance with 37 CFR 1.67(a) identifying this application by application number and filing date is required. See MPEP §§ 602.01 and 602.02.

The oath or declaration is defective because:

It does not identify the mailing address of each inventor. A mailing address is an address at which an inventor customarily receives his or her mail and may be either a home or business address. The mailing address should include the ZIP Code designation. The mailing address may be provided in an application data sheet or a supplemental oath or declaration. See 37 CFR 1.63(c) and 37 CFR 1.76.

It does not identify the city and either state or foreign country of residence of each inventor. The residence information may be provided on either an application data sheet or supplemental oath or declaration.

#### **Drawings**

The drawings dated 1/30/04 have been accepted.

## Specification

The disclosure is objected to because of the following informalities listed below.

Appropriate correction is required.

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The attempt to incorporate subject matter into this application by reference to 09/927648, 10/326470, and 10/036291 in paragraphs 48 and 51 are improper because there is no recitation that the application is commonly assigned. Reliance on a commonly assigned copending application by a different inventor may ordinarily be made for the purpose of completing the disclosure. See In re Fried, 329 F.2d 323, 141 USPQ 27, (CCPA 1964), and General Electric Co. v. Brenner, 407 F.2d 1258, 159 USPQ 335 (D.C. Cir 1968).

### Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

This application currently names joint inventors. In considering patentability of the claims under 35 U.S.C. 103(a), the examiner presumes that the subject matter of the various claims was commonly owned at the time any inventions covered therein were made absent any evidence to the contrary. Applicant is advised of the obligation under 37 CFR 1.56 to point out the inventor and invention dates of each claim that was not commonly owned at the time a later invention was made in order for the examiner to consider the applicability of 35 U.S.C. 103(c) and potential 35 U.S.C. 102(e), (f) or (g) prior art under 35 U.S.C. 103(a).

Claims 1-16 are rejected under 35 U.S.C. 103(a) as being unpatentable over Mitani et al. (5,864,161). Mitani discloses a method of forming a semiconductor device in which silane and boron trichloride can be reacted to form a polysilicon film (col.12 lines 8-17 and col.15 lines 32-38). Specifically, the reference teaches that boron, phosphorus, or arsenic can be used as the

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impurity (col.7 lines 17-18). The desired boron concentration can be  $1x10^{19}$  to  $1x10^{22}$  atoms/cc (col.16 lines 15-22). However, the reference fails to teach the appropriate dopant concentration.

It is noted that the reference clearly teaches a boron concentration of  $1x10^{19}$  to  $1x10^{22}$  atoms/cc which overlaps the claimed range. Overlapping ranges are *prima facie* evidence of obviousness. It would have been obvious to one having ordinary skill in the art to have selected the portion of Mitani's range of concentration that corresponds to the claimed range.

The limitations of claims 2-16 have been addressed above.

Claims 1-16 are rejected under 35 U.S.C. 103(a) as being unpatentable over

Freeman (5,096,856) in view of Mitani et al. (5,864,161). Freeman discloses a method of
forming in situ phosphorous doped polysilicon upon a surface in which a predetermined ratio of
silane and a gaseous phosphorous containing compound such as phosphorous trichloride are
simultaneously passed through a furnace at predetermined pressure and temperature to provide a
uniformly phosphorous doped layer of polysilicon on the surface (col.1 lines 10-13 and col.2
lines 7-11. The pressure can be 10-20 mTorr and the temperature can be about 500 to 700 °C
(col.2 lines 11-16). However, the Freeman fails to teach the appropriate doping concentrations
as well as the appropriate pressure and temperature.

It is noted that the reference clearly teaches that flow rates, temperature and pressure affect the buildup of phosphorous (col.3 lines 1-17). Given such a teaching, one skilled in the art would realize that temperature, pressure, and flow rates would affect the phosphorous concentration. Hence, it would have been obvious to the skilled artisan to optimize the

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appropriate deposition parameters including temperature, pressure, and flow rates with the expectation of obtaining the claimed doping concentrations.

In addition, the reference fails to teach boron trichloride.

Mitani discloses of forming a semiconductor device in which silane and boron trichloride can be reacted to form a silicon film (col.12 lines 8-17). Specifically, the reference teaches that boron, phosphorus, or arsenic can be used as the impurity (col.7 lines 17-18). One skilled in the art would realize, after reading Mitani, the boron and phosphorus are conventionally used as dopants in a semiconductor device and that boron trichloride is a conventional precursor to utilize to form the boron dopant. It would have been obvious to substitute a boron dopant for use in Freeman's process because Mitani teaches that boron and phosphorus are conventionally used as dopants. Furthermore, it would have been obvious to utilize boron trichloride to form a boron dopant because Mitani teaches the conventionality of utilizing same to form the dopant.

The limitations of claims 2-16 have been addressed above.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to B. Chen whose telephone number is (571) 272-1417. The examiner can normally be reached on 7:30am - 4:00pm.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Timothy Meeks can be reached on (571) 272-1423. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Bc

2/1/06

BRET CHEN
PRIMARY EXAMINER